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If the sum of \$180.00 is due under 37 CFR § 1.17(p) pursuant to § 1.97, the Commissioner is hereby authorized to charge this fee, and any other fee necessary to make this submission timely, to the Deposit Account No. 20-0782/AMAT/6218/DD/LOW K/JW.

Respectfully submitted,



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U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)					Docket No. AMAT/6218/DD/LOW K/JW		Serial No. 10/092,203	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Applicant Lang et al.		Confirmation No.: Unknown	
(Use several sheets if necessary)					Filing Date March 4, 2002		Group Unknown	
Examiner Unknown								
U.S. Patent Documents								
*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate	
	A1	6,312,793	11/06/2001	Grill et al.	428	312.6	05/26/1999	
	A2	6,287,990	09/11/2001	Cheung et al.	438	780	09/29/1998	
	A3	6,159,871	12/12/2000	Loboda et al.	438	786	05/29/1998	
	A4	6,147,009	11/14/2000	Grill et al.	438	780	06/29/1998	
	A5	6,051,321	04/18/2000	Lee et al.	428	447	10/24/1997	
	A6	5,989,998	11/23/1999	Sugahara et al.	438	623	08/28/1997	
	A7	5,818,071	10/06/1998	Loboda et al.	257	77	02/02/1995	
	A8	5,711,987	01/27/1998	Bearinger et al.	427	7	10/04/1996	
	A9	5,465,680	11/14/1995	Loboda	117	84	07/01/1993	
	A10							
	A11							
	A12							
Foreign Patent Documents								
*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
	B1						YES <input type="checkbox"/>	NO <input type="checkbox"/>
	B2						YES <input type="checkbox"/>	NO <input type="checkbox"/>
OTHER ART								
*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.						
	C1	Huang, et al., USSN 09/902,518, filed July 10, 2001, "Method and Apparatus for Treating Low <i>k</i> Dielectric Layers to Reduce Diffusion"						
	C2	Campana, et al., USSN 09/793,818, filed Feb. 23, 2001, "Method of Depositing Low Dielectric Constant Silicon Carbide Layers"						
	C3	Nemani, et al., USSN 09/627,667, filed July 28, 2000, "Method of Depositing Dielectric Films"						
Examiner					Date Considered			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								

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